

# Material Engineering for 7nm FinFETs

Victor Moroz

July 10, JTG Semicon West 2014,  
San Francisco

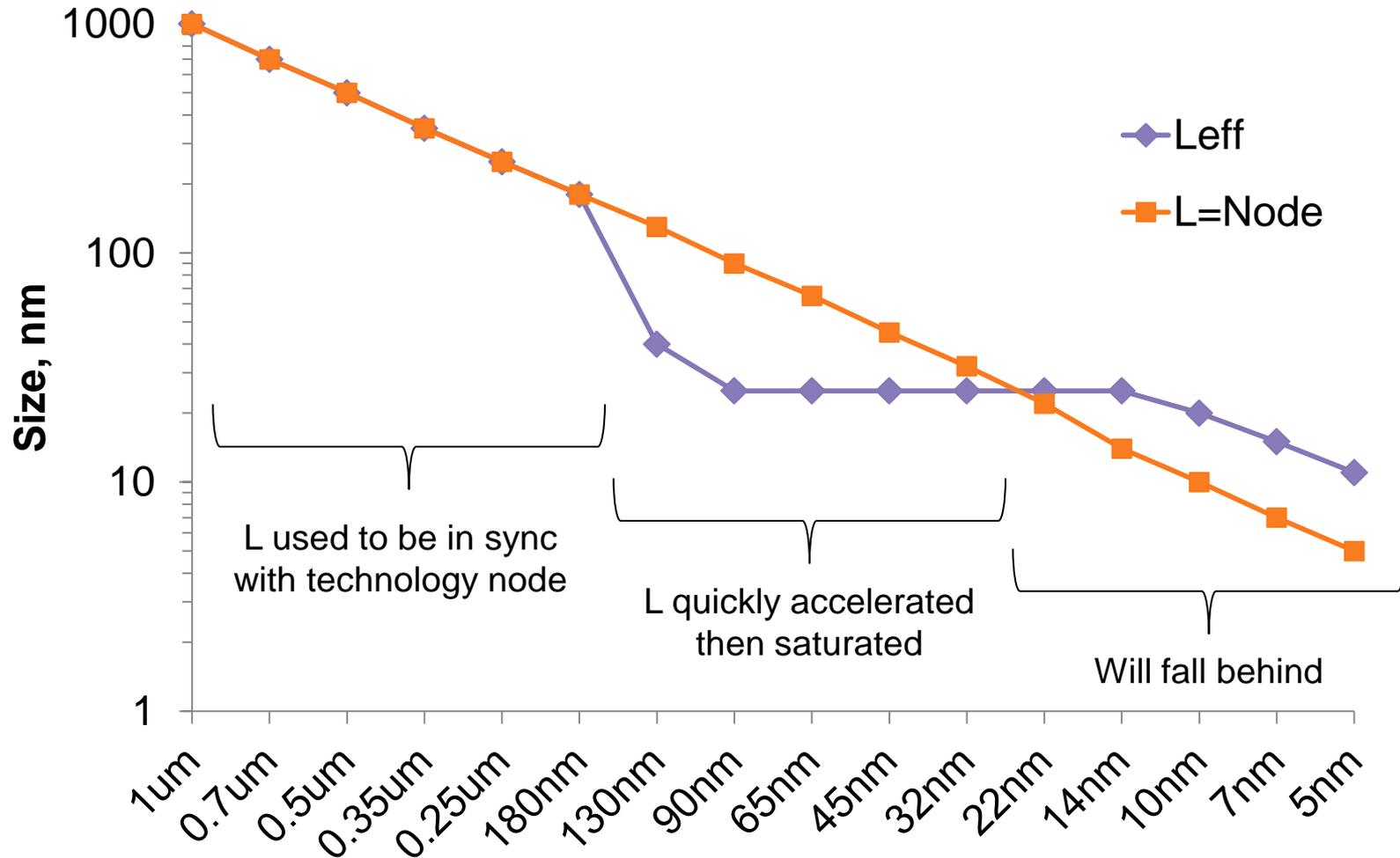
# Outline

- **Introduction**
- **Group IV FinFETs**
- **III-V FinFETs**
- **Summary**

# Outline

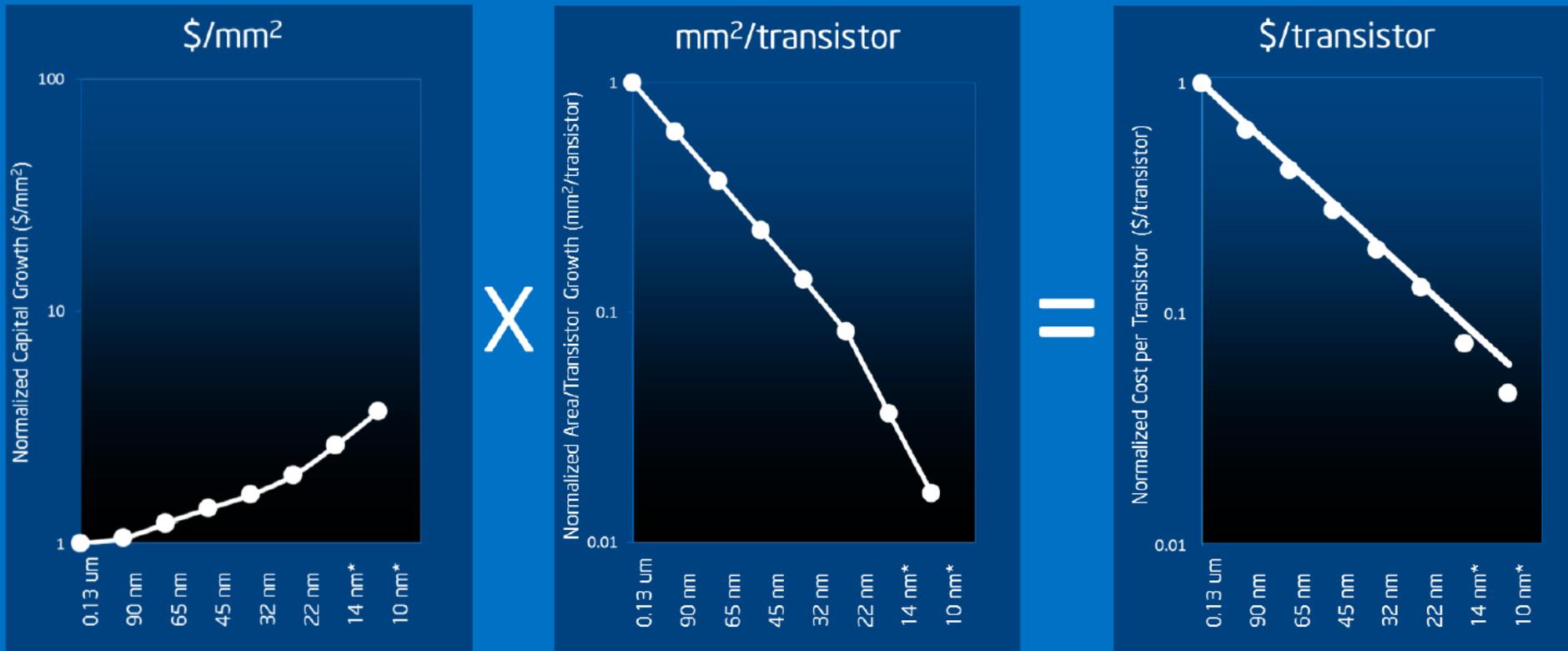
- **Introduction**
- Group IV FinFETs
- III-V FinFETs
- Summary

# Evolution of Transistor Scaling



# Intel Investor Meeting, Nov. 21, 2013

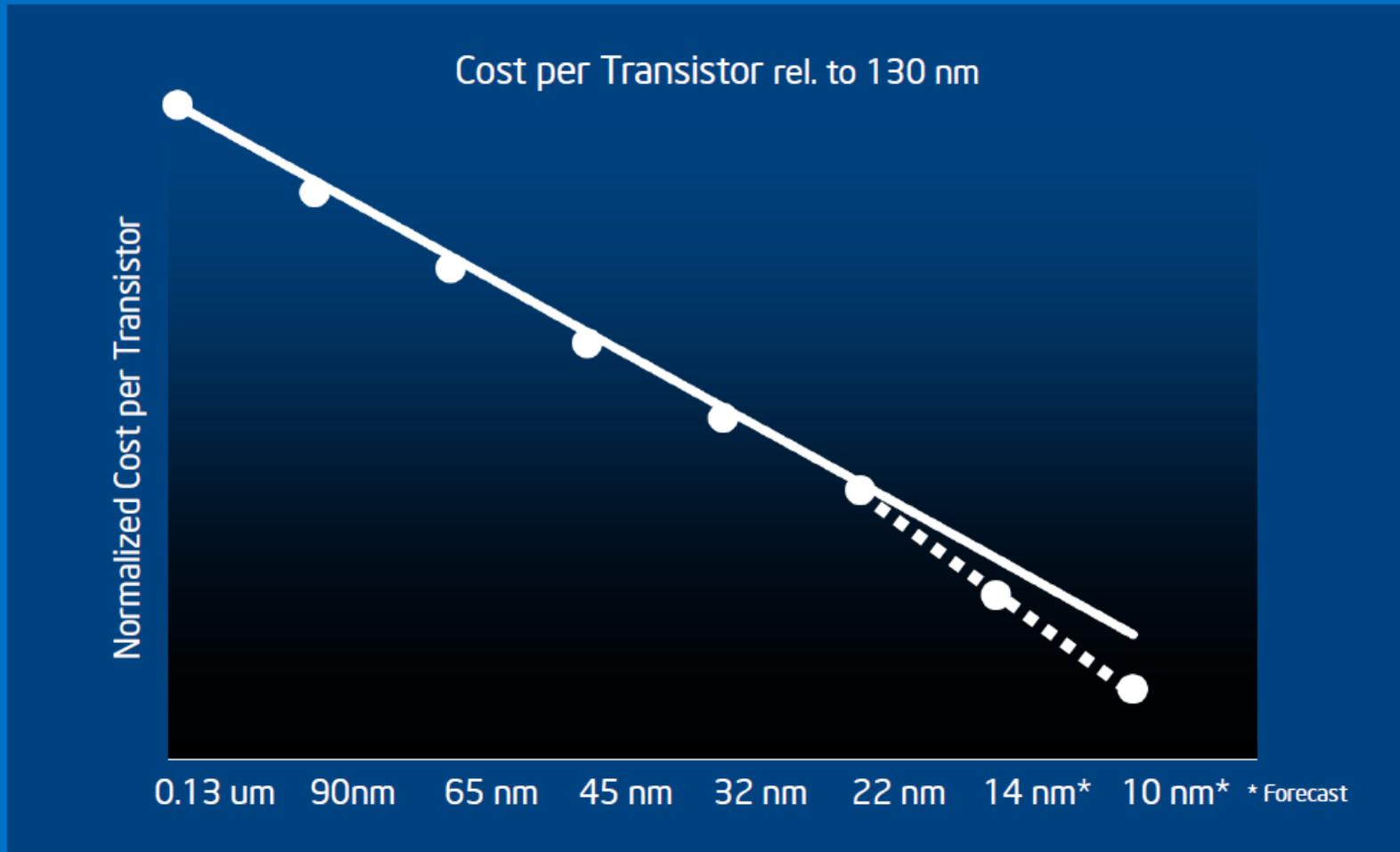
## Density Improvements Offset Wafer Cost Trends



Source: Intel

\* Forecast

# Density Scaling ~~Continues~~ Cost Improvement Accelerates



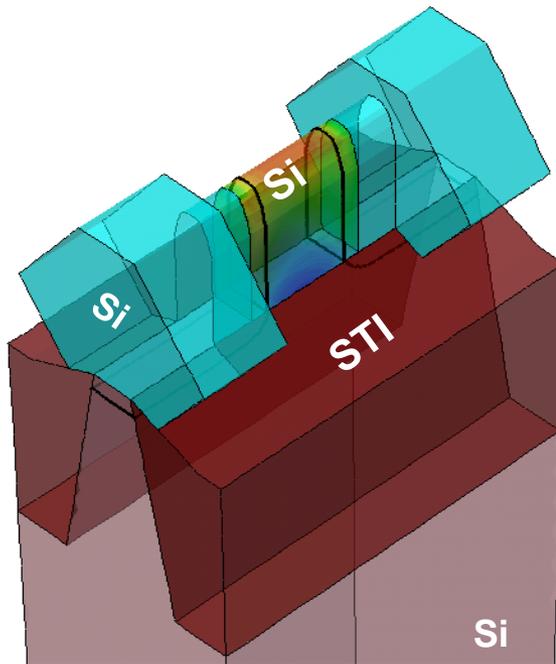
Source: Intel

# Expected Design Rules

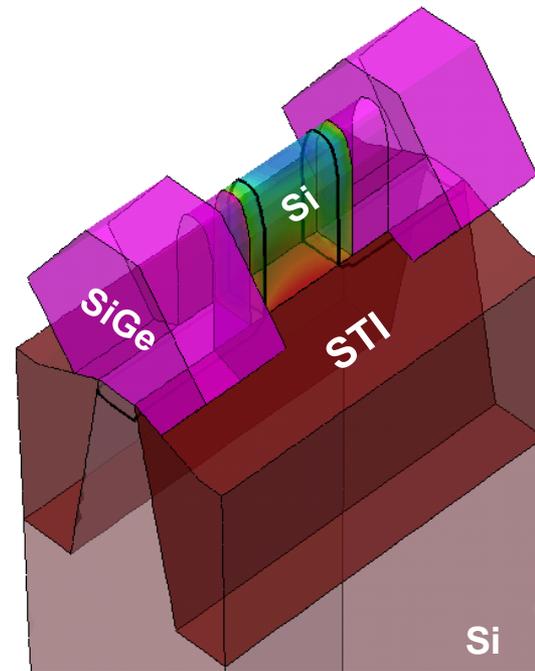
Node	Gate pitch	L	Spacer	Fin width	Fin height	Fin pitch	Contact size	EOT
10	63	20	11	8	32	34	21	0.85
7	44	15	7	6	30	24	15	0.8

# Stress Engineering at 14 nm Node

NMOS: Low Stress



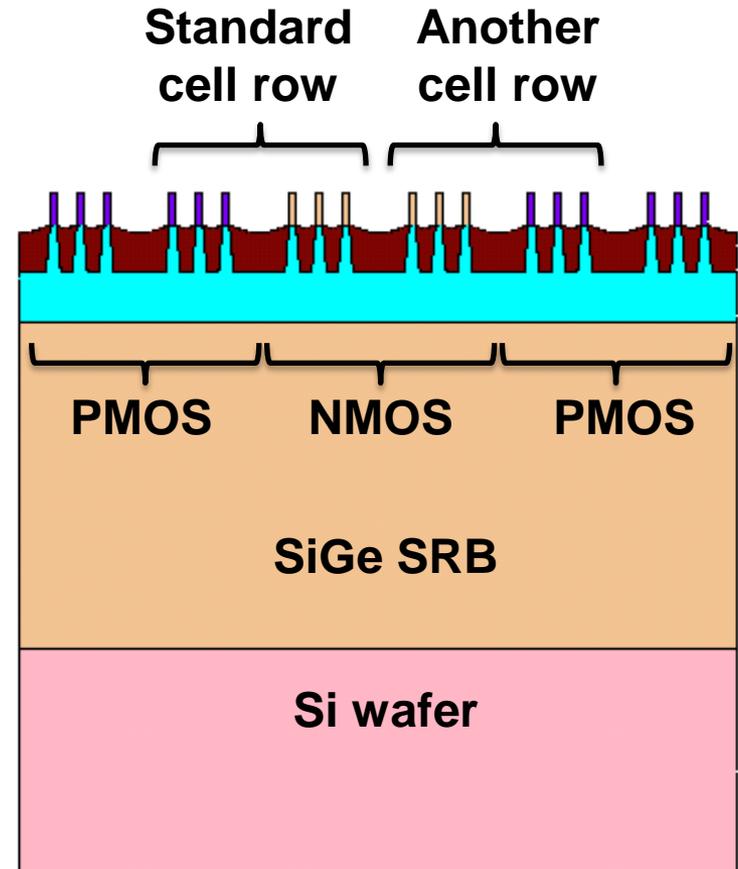
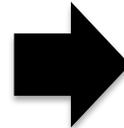
PMOS: High Stress



- Main stress source is SiGe PMOS source/drain epitaxy

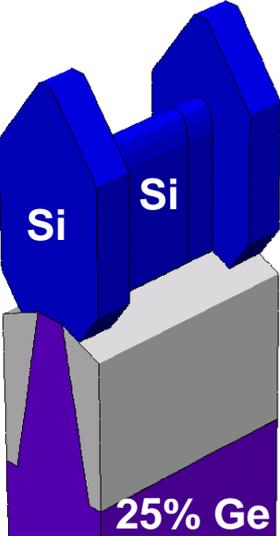
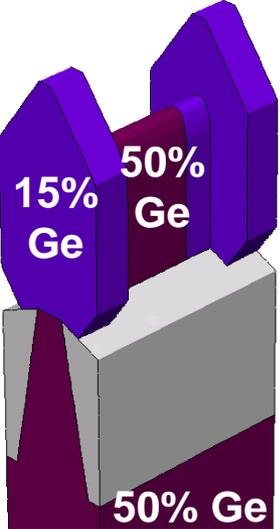
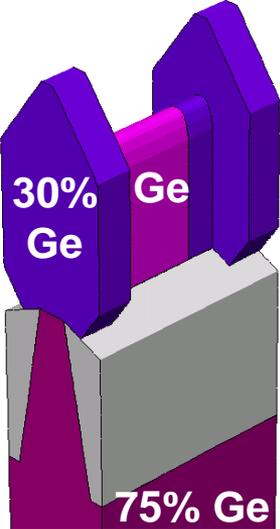
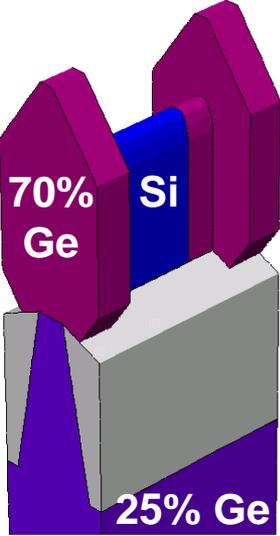
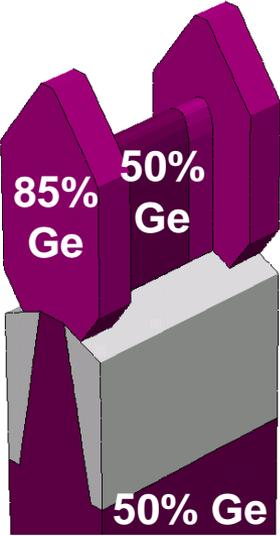
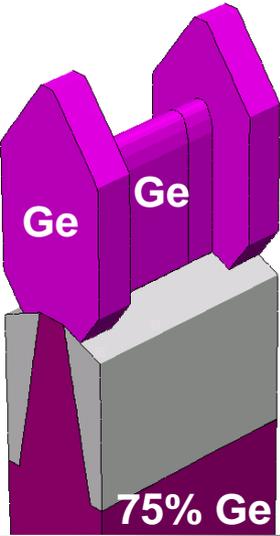
# Common SRB Epi for NMOS & PMOS

Wafer before fin patterning

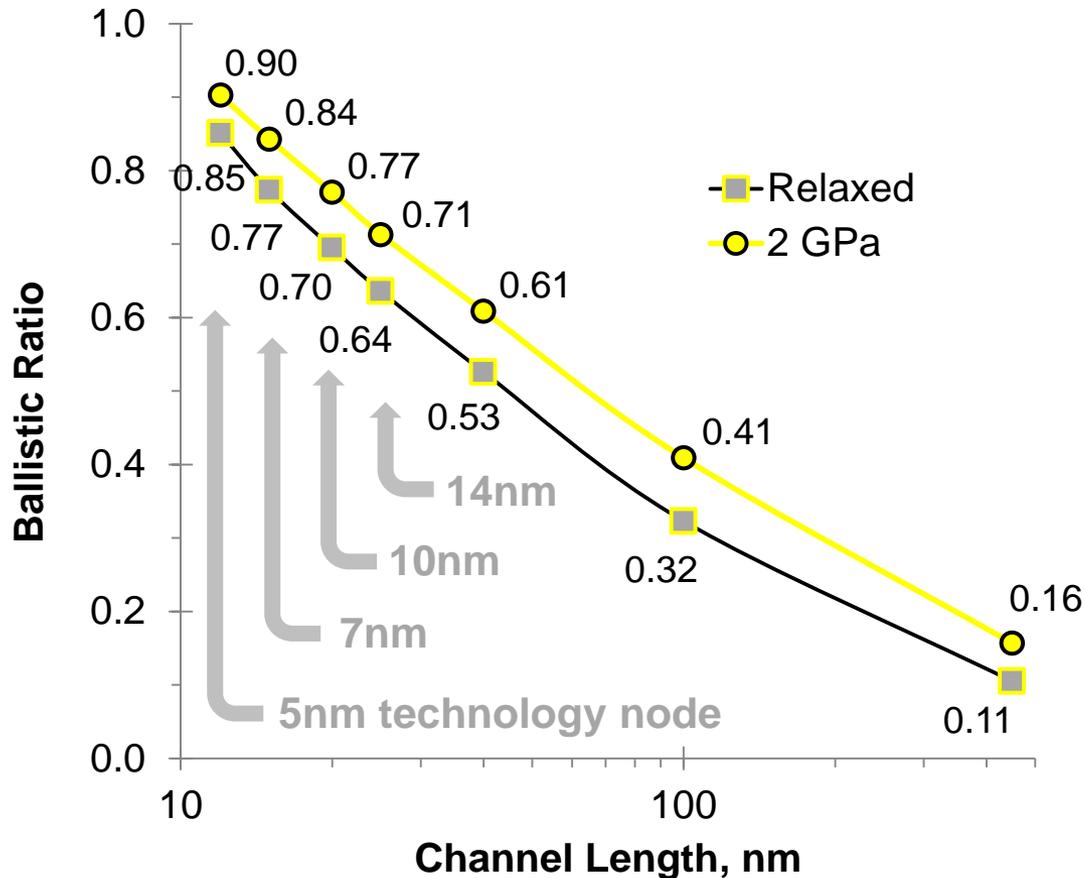


- Considering cell heights (itches) of 360 nm, it is impractical to have separate SRB's for NMOS and PMOS

# 7nm Stress Engineering: SRB + S/D Epi

	Si channel	SiGe channel	Ge channel
<b>NMOS</b> <b>+1.5 GPa</b>	 <p>Si Si 25% Ge</p>	 <p>15% Ge 50% Ge 50% Ge</p>	 <p>30% Ge Ge 75% Ge</p>
<b>PMOS</b> <b>-1.5 GPa</b>	 <p>70% Ge Si 25% Ge</p>	 <p>85% Ge 50% Ge 50% Ge</p>	 <p>Ge Ge 75% Ge</p>

# Ballistic Transport Evolution



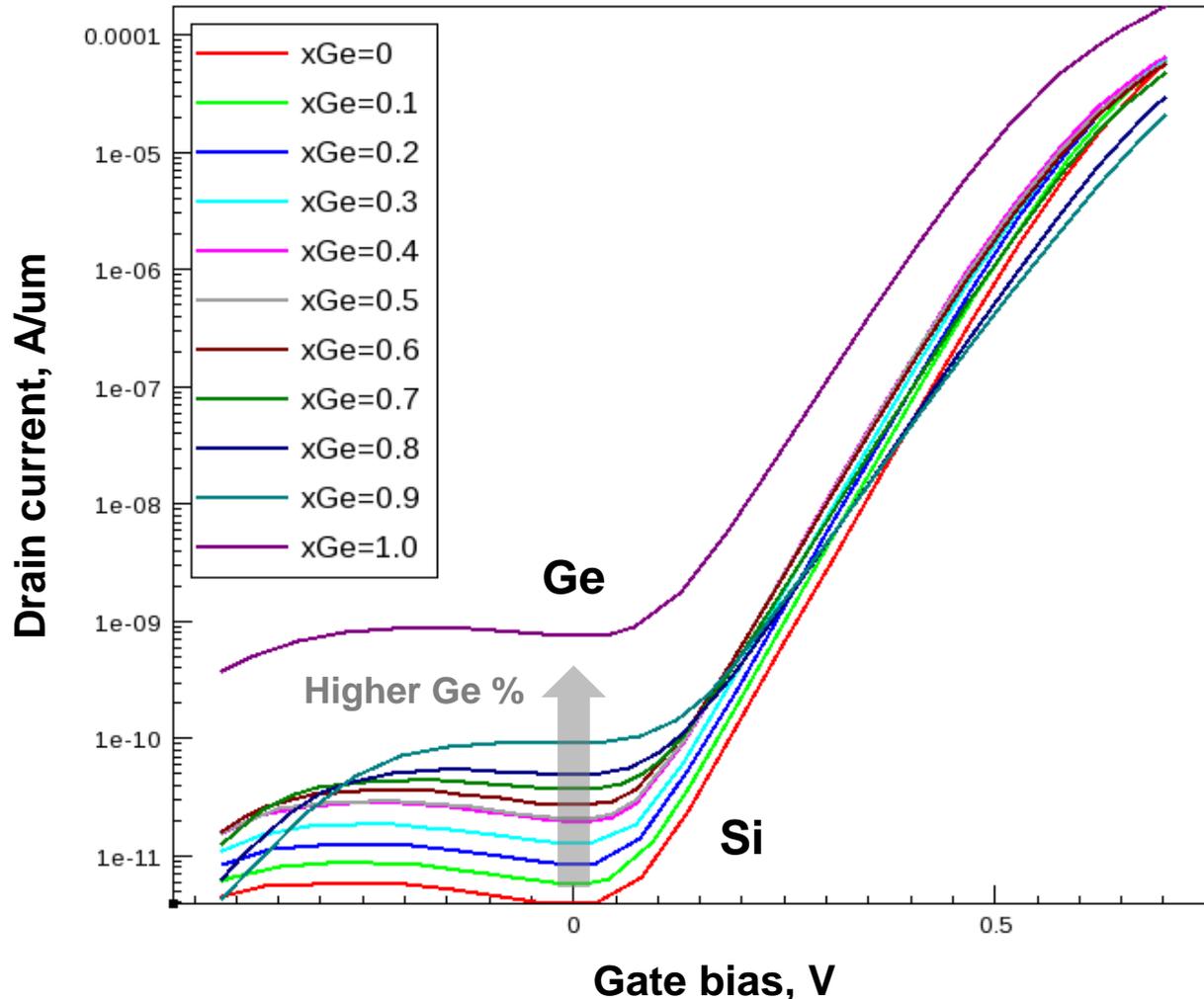
*Si NMOS FinFET with 6nm wide fin*

- Ballistic transport is currently ~64%
- Is expected to rise to ~84% at 7nm node
- Even higher for Ge and InGaAs
- Therefore, ballistic transport approximation is reasonable for 7nm node

# Outline

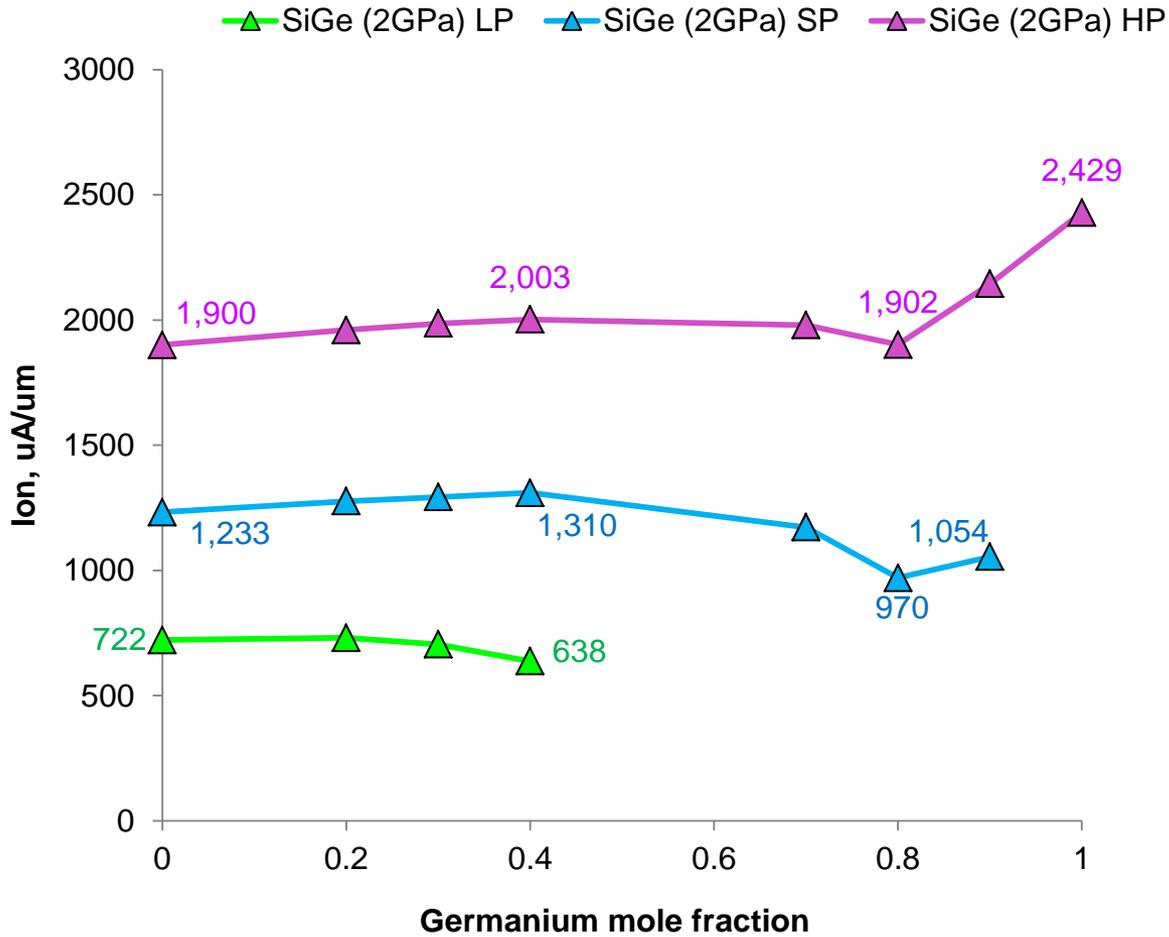
- Introduction
- **Group IV FinFETs**
- III-V FinFETs
- Summary

# Stress Free SiGe: IdVg Curves



- $V_{dd} = 0.7$  V in this project
- BTBT model calibrated by IMEC

# Strained SiGe: 2 GPa Tensile Stress

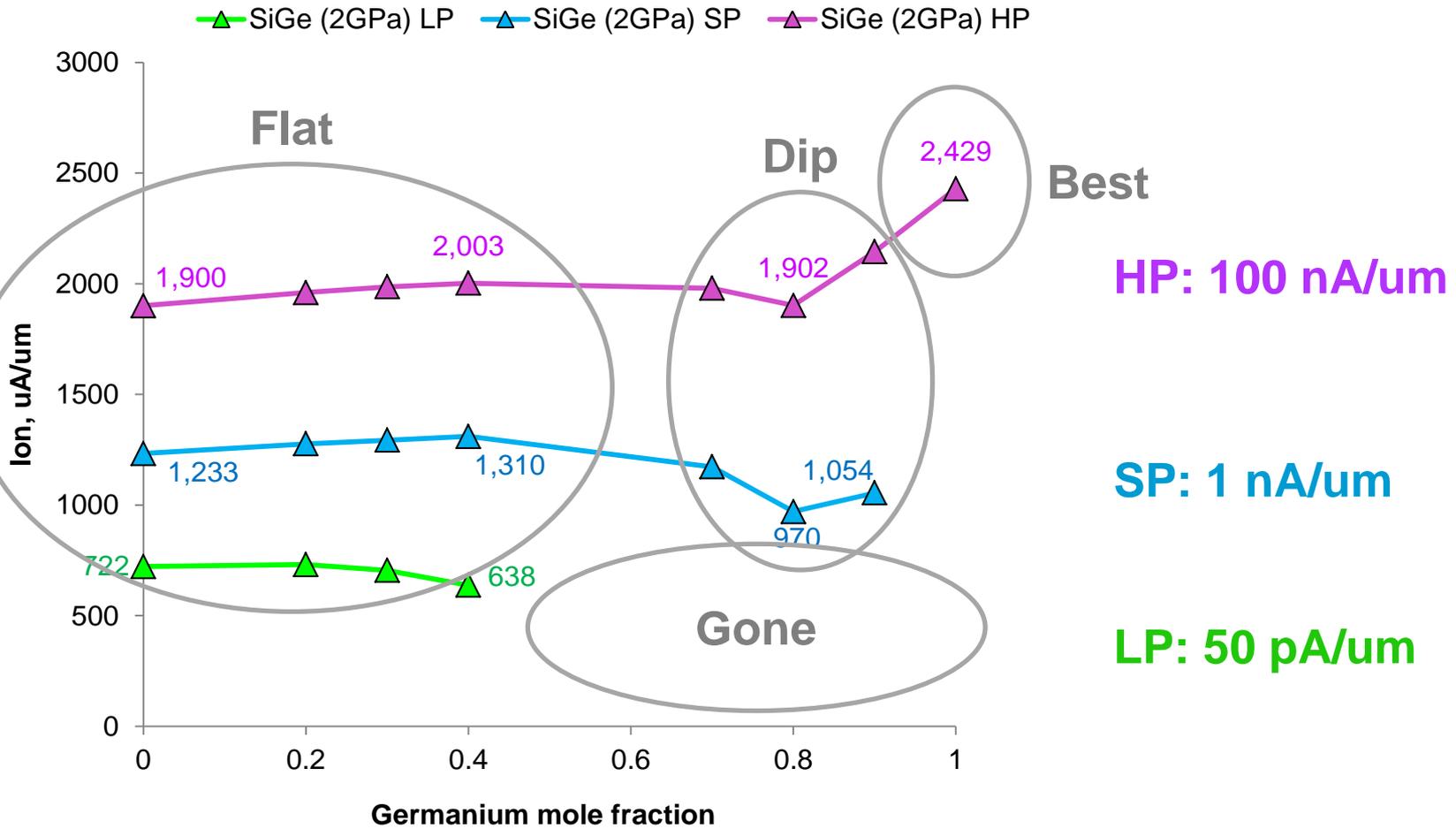


**HP: 100 nA/um  
(Servers)**

**SP: 1 nA/um  
(Laptops)**

**LP: 50 pA/um  
(Mobile)**

# Strained SiGe: 2 GPa Tensile Stress

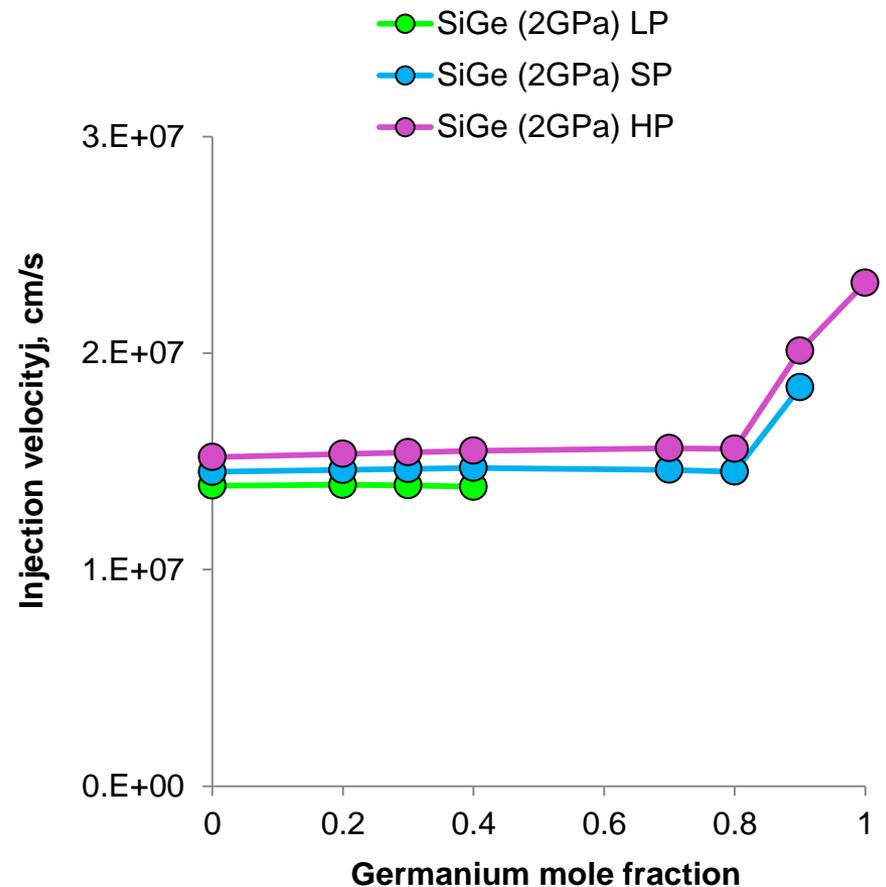
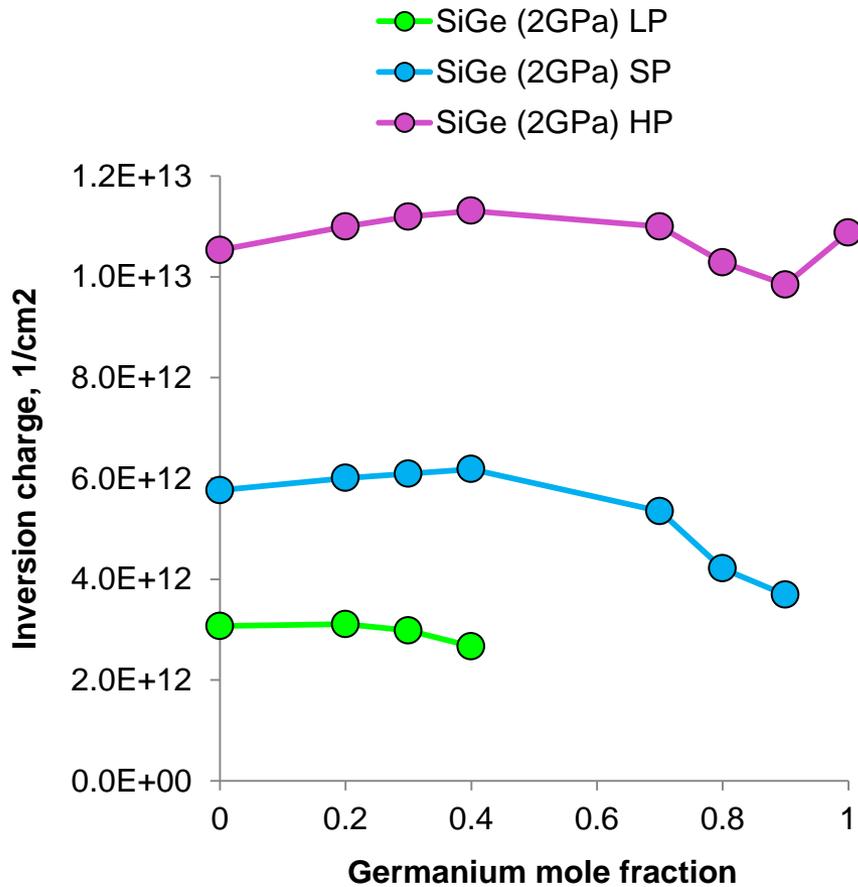


HP: 100 nA/um

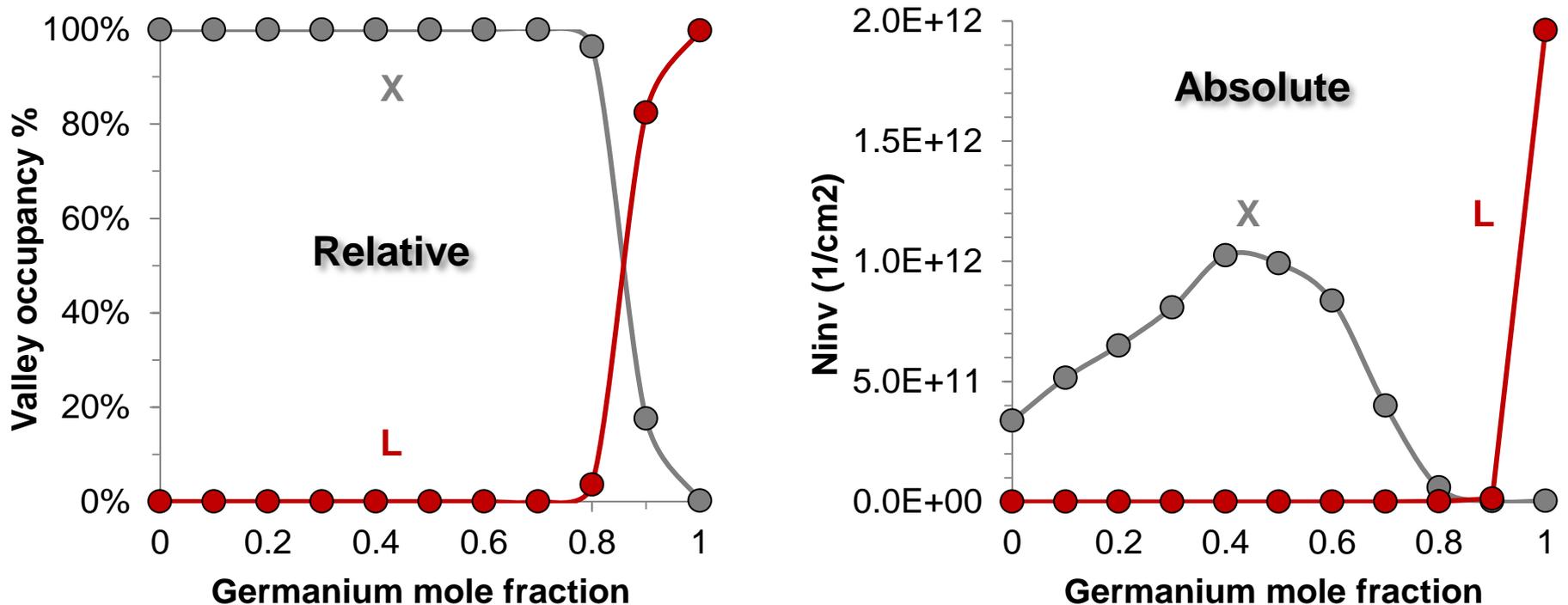
SP: 1 nA/um

LP: 50 pA/um

# Strained SiGe: $N_{inv}$ and $V_{inj}$

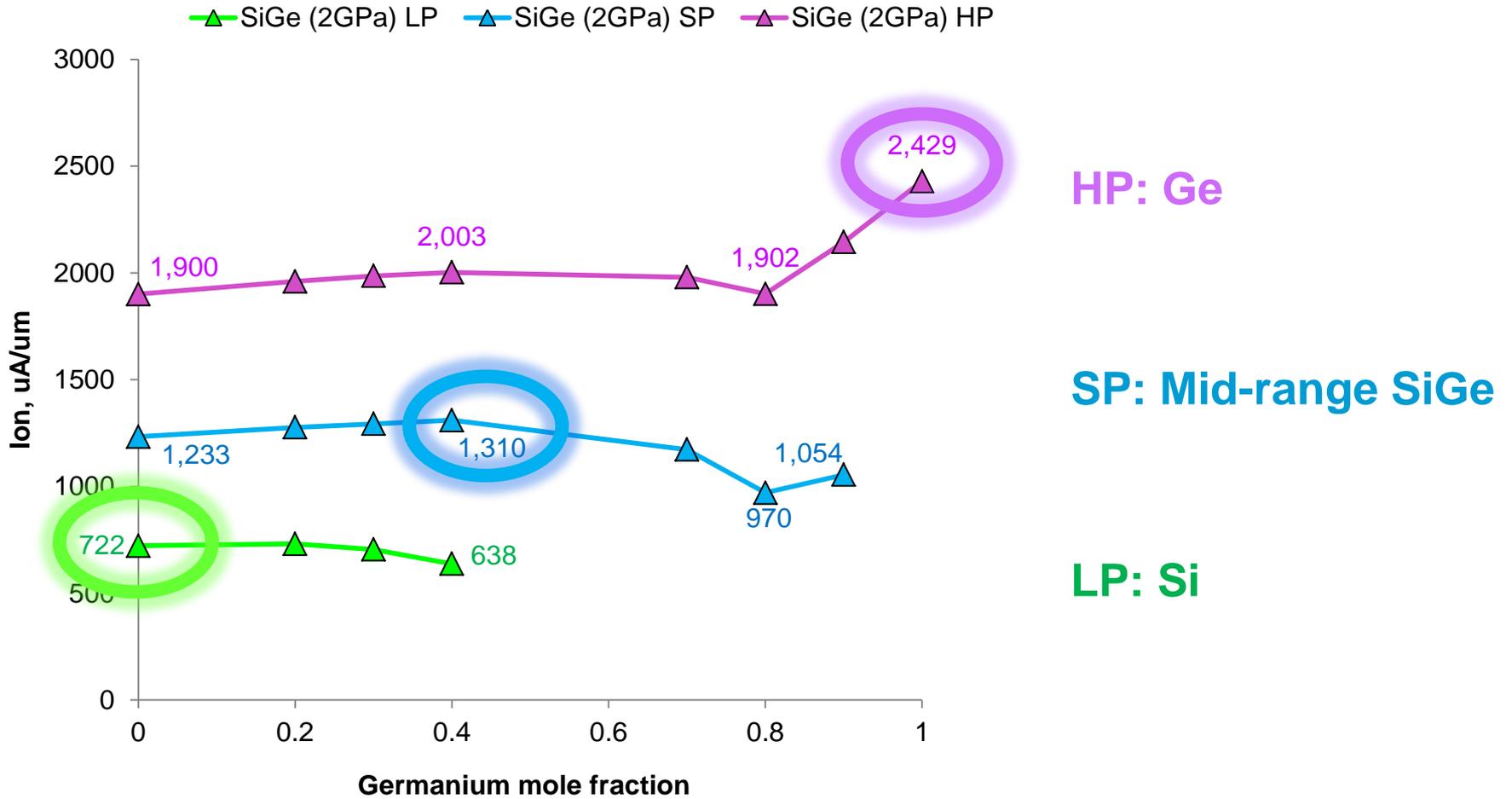


# Delta & Lambda Valley Population

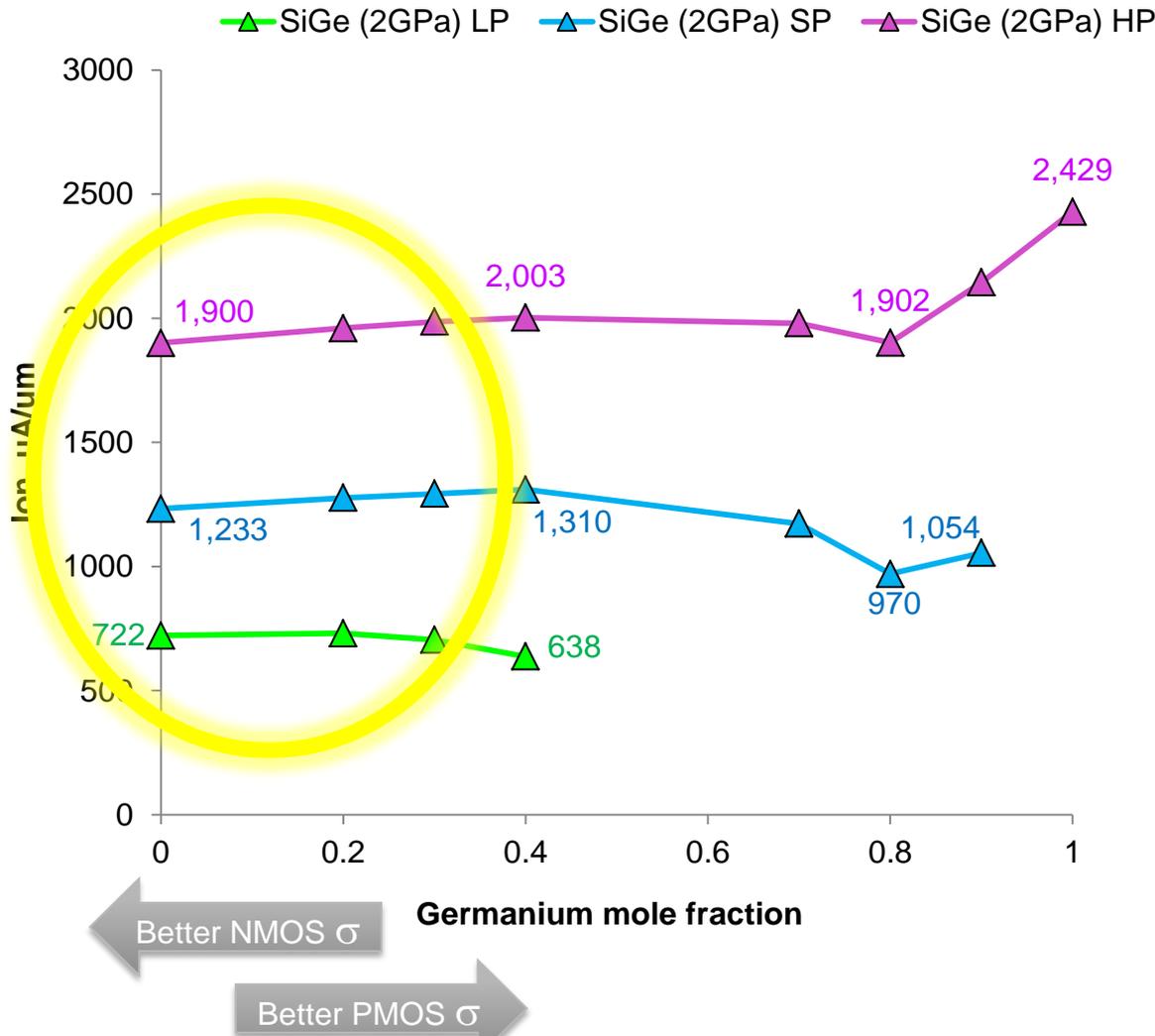


- Here,  $V_{gs} = 0.7$  V and gate WF is adjusted to have min loff at  $V_{gs} = 0$
- There are too few electrons at 80% to 90% Ge mole fractions

# Strained SiGe: LP, SP & HP Champions



# Strained SiGe: Combination Champion

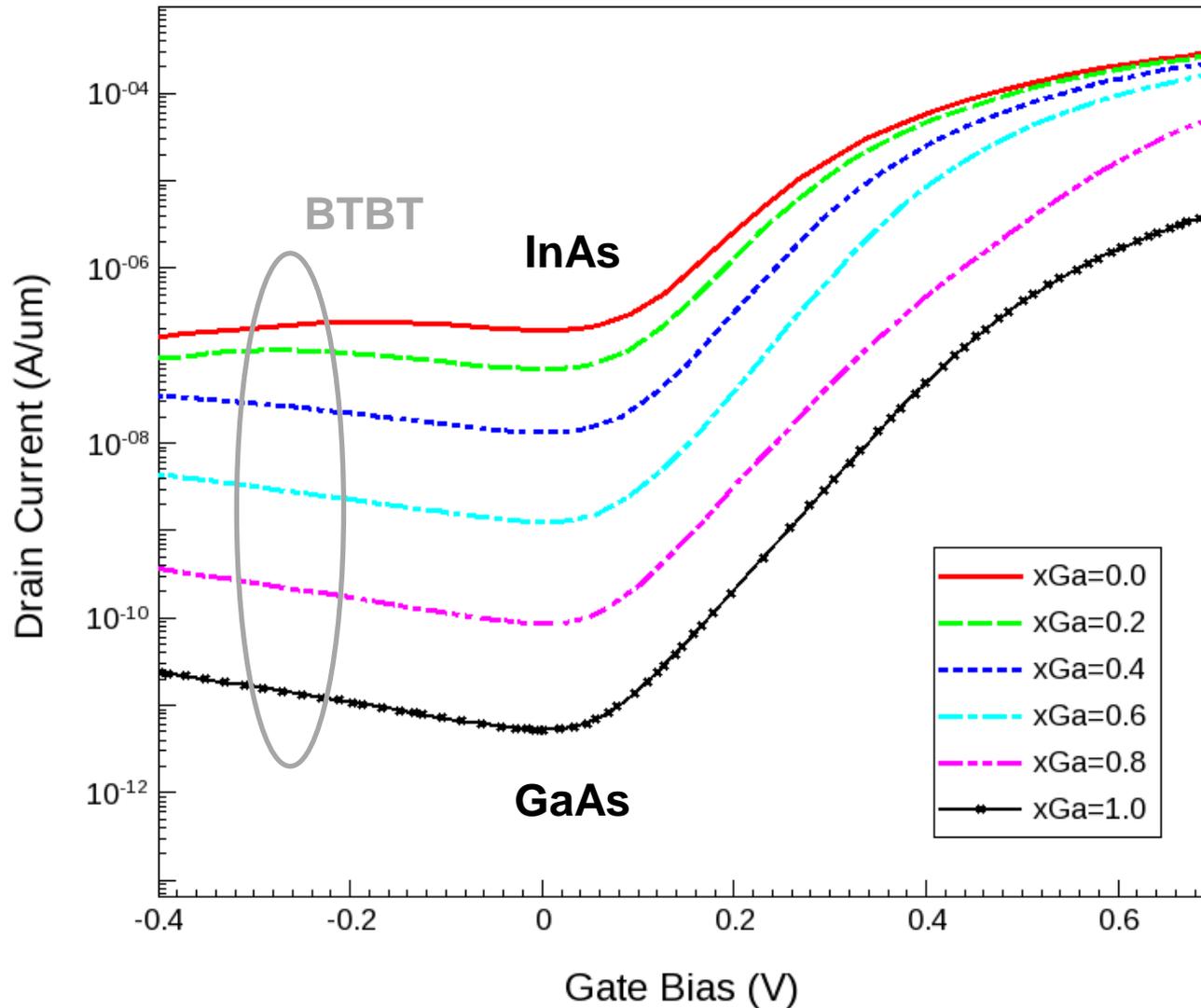


- Only Si and SiGe with low Ge % can match LP spec
- HP performance penalty to pure Ge is ~20%
- The choice between pure Si vs SiGe with low Ge % can be made based on PMOS/NMOS stress trade-off

# Outline

- Introduction
- Group IV FinFETs
- **III-V FinFETs**
- Summary

# IdVg After Work-Function Adjustment

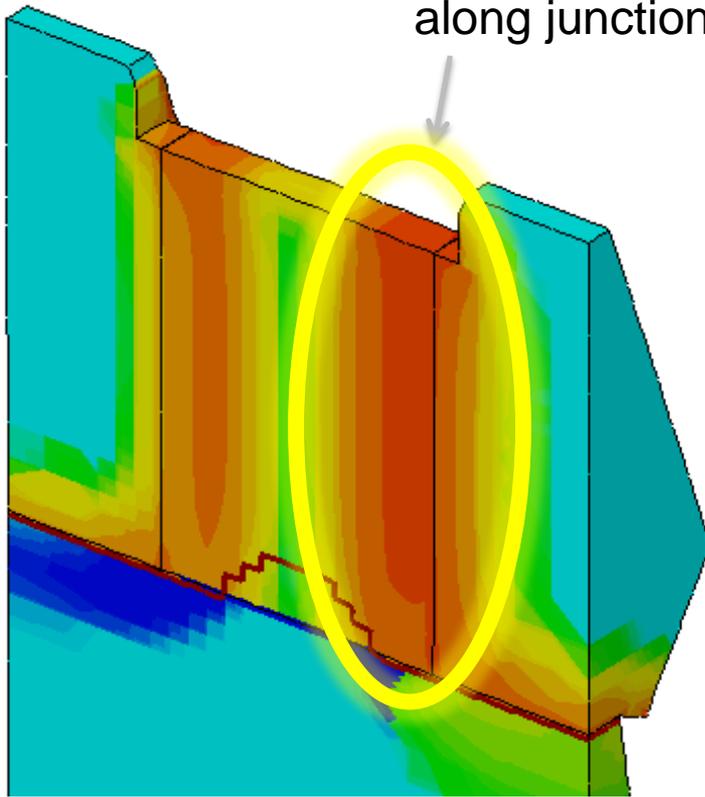


- BTBT model calibrated by IMEC
- Vdd = 0.7 V

# Leakage Patterns

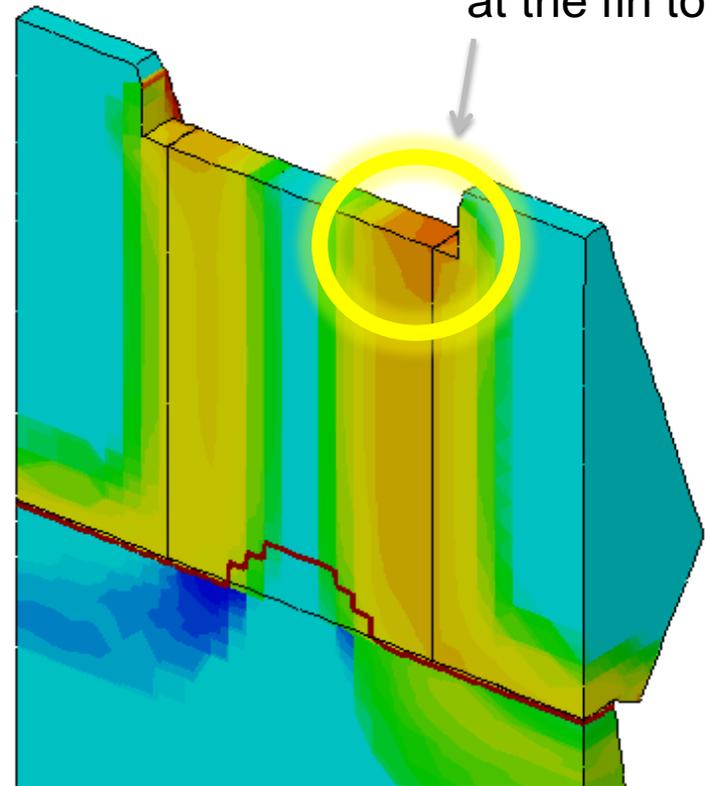
## InAs

BTBT is spread  
along junction

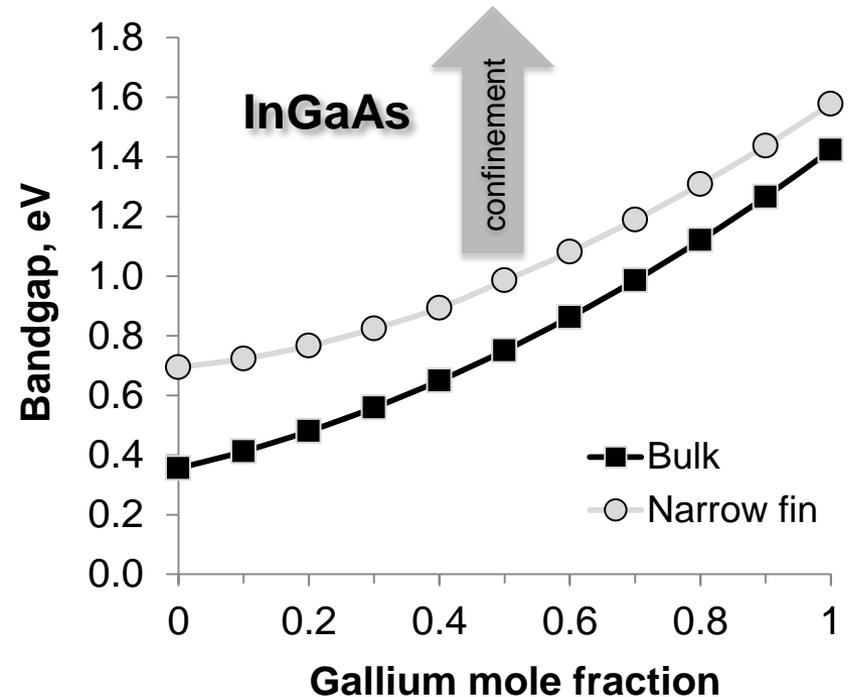
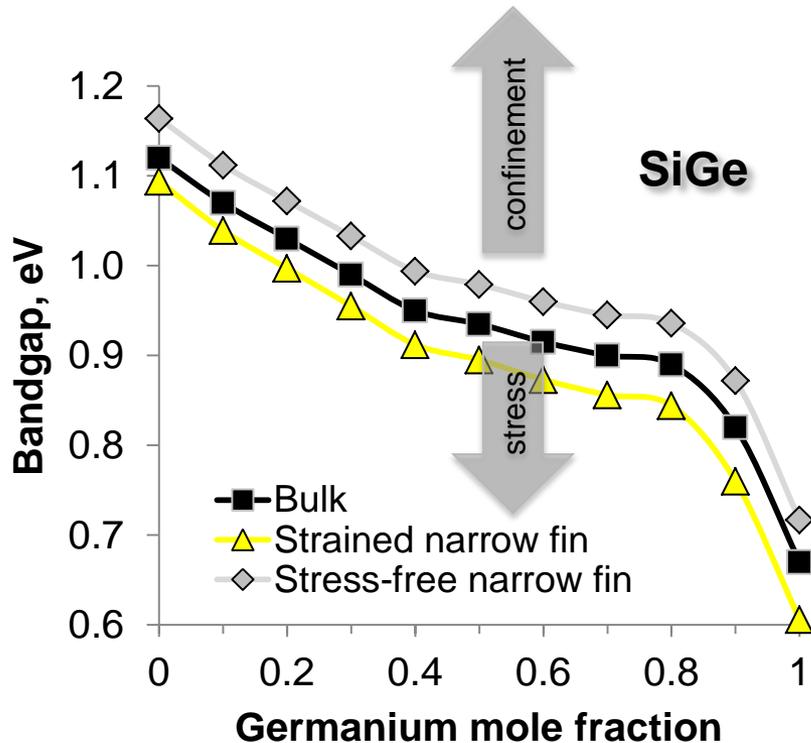


## GaAs

GIDL happens  
at the fin top

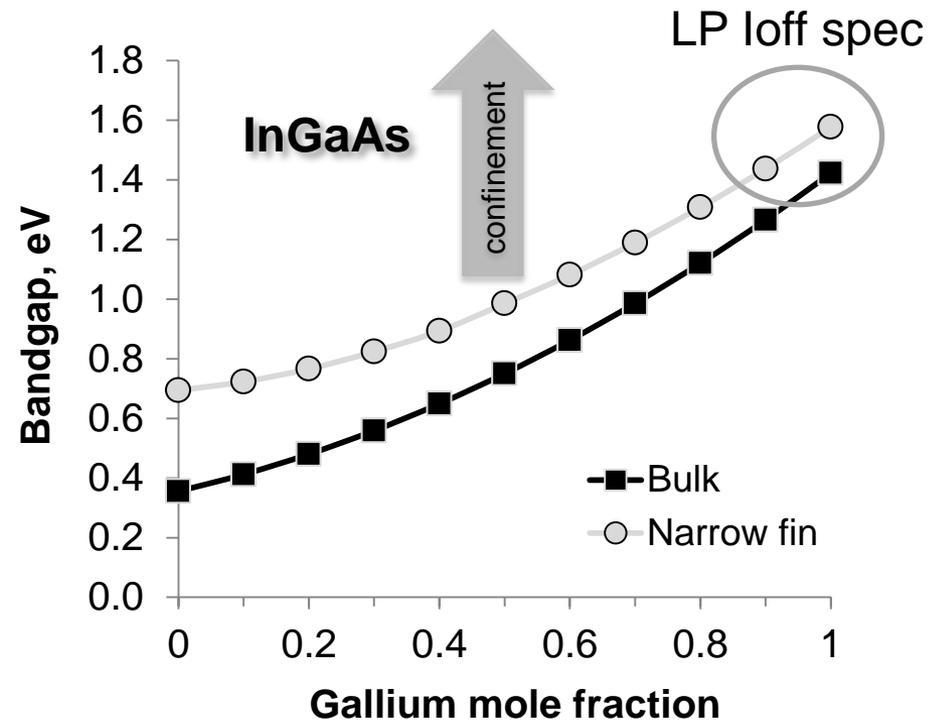
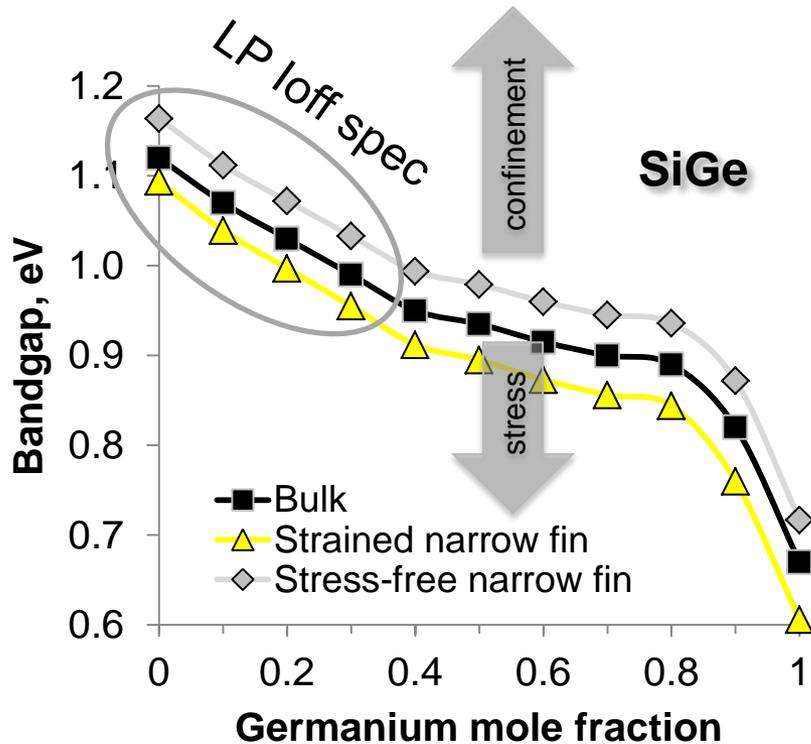


# Band Gap Widening and Narrowing



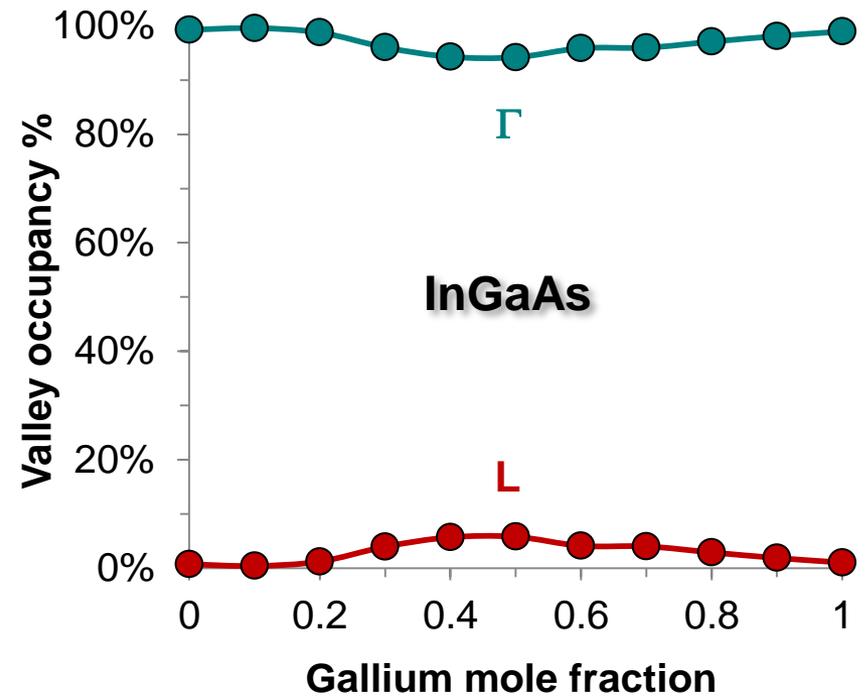
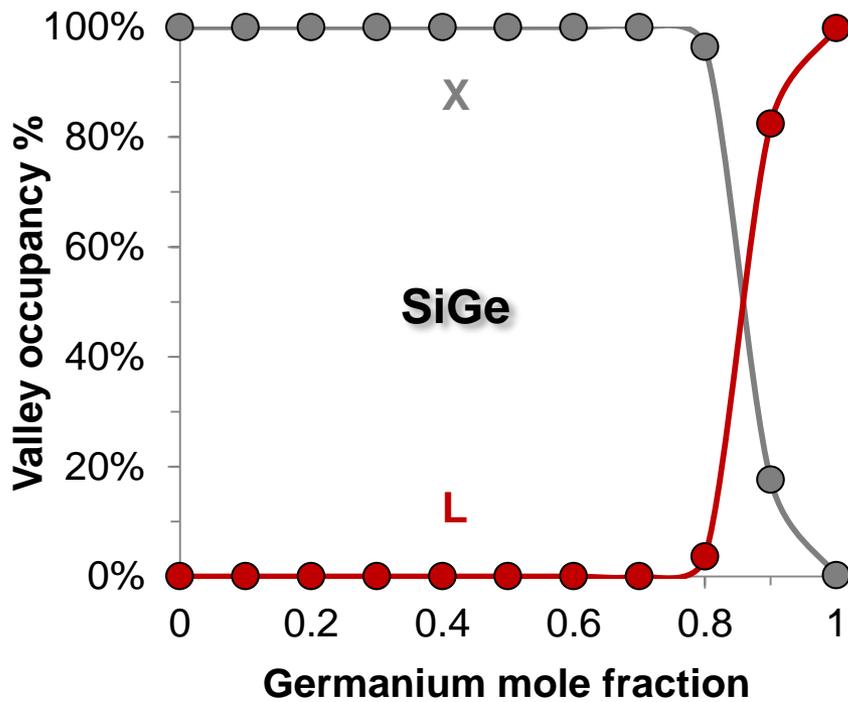
- For SiGe, 6nm wide fin widens bandgap by 40 mV to 50 mV
- Tensile uniaxial 2 GPa stress pushes it down by 70 mV to 100 mV
- For GaAs, the widening is 155 mV, and for InAs it grows to 340 mV

# Band Gap Widening and Narrowing



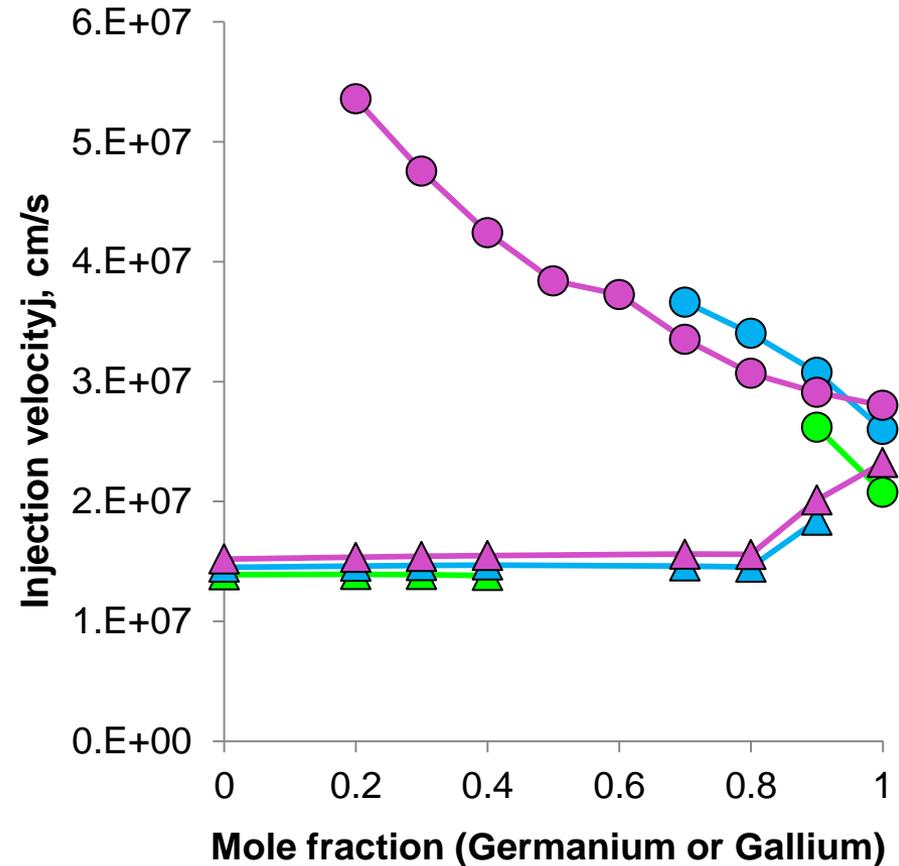
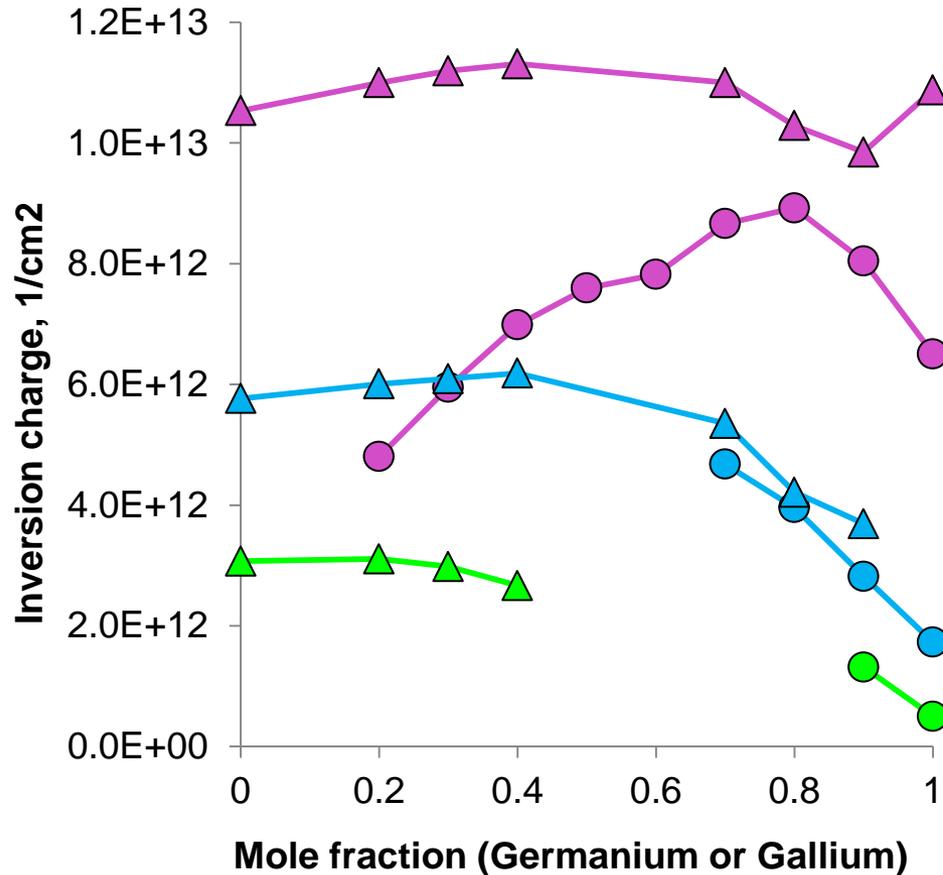
- High mobility materials need to have bandgap wider than silicon!

# Gamma, Delta & Lambda Valleys

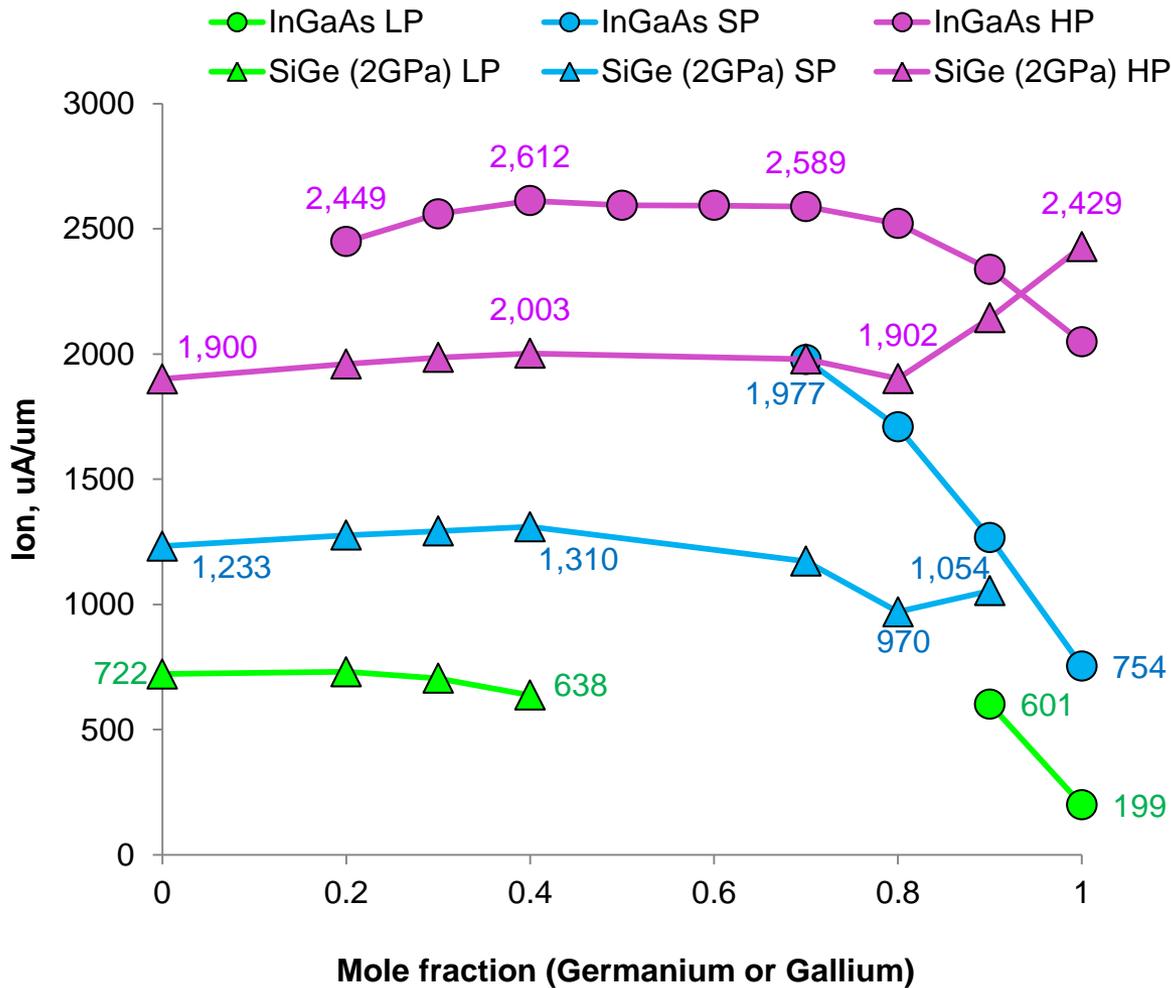


# Group IV vs III-V: $N_{inv}$ and $V_{inj}$

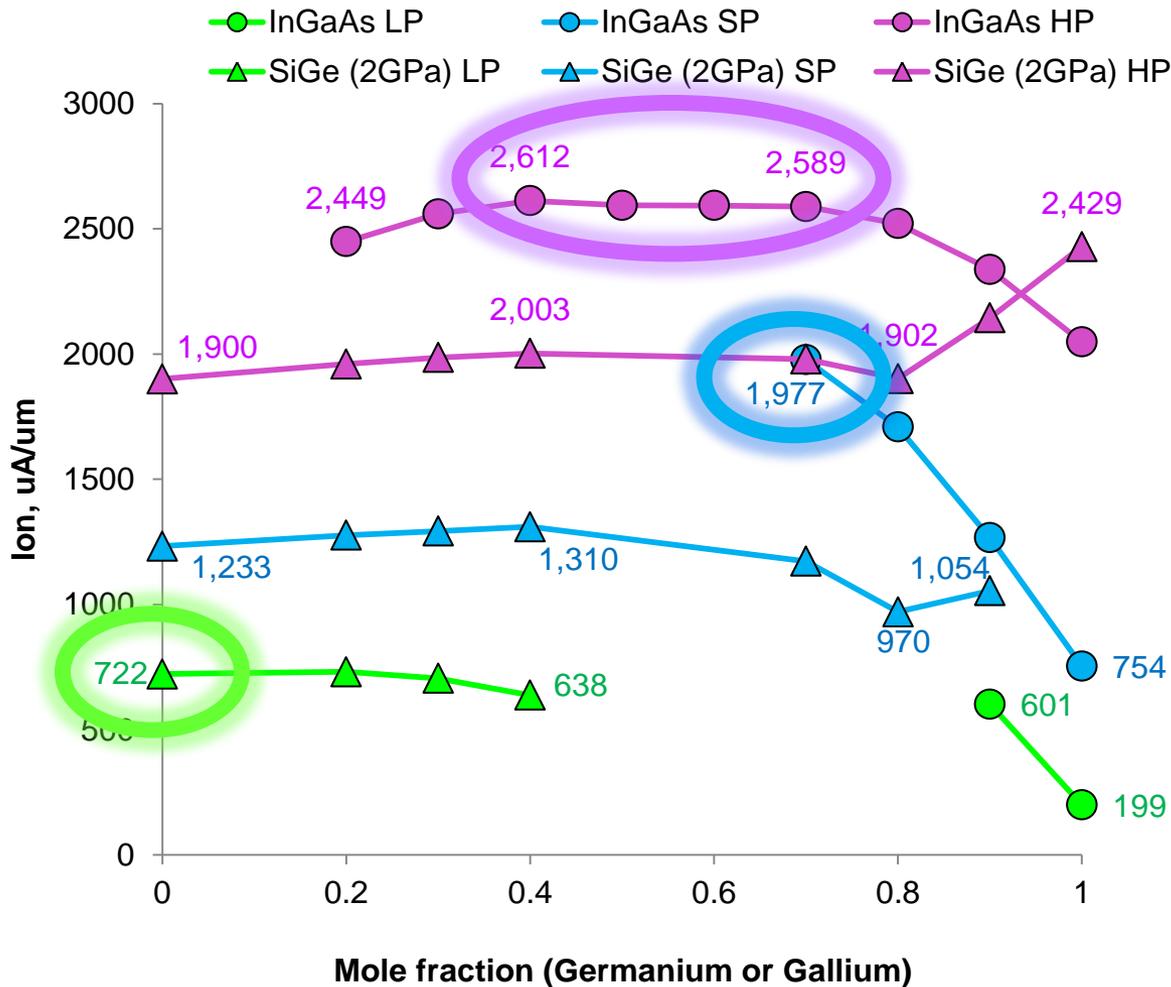
- InGaAs LP      ● InGaAs SP      ● InGaAs HP
- ▲ SiGe (2GPa) LP      ▲ SiGe (2GPa) SP      ▲ SiGe (2GPa) HP



# Group IV vs III-V



# Group IV vs III-V: LP, SP & HP Champions

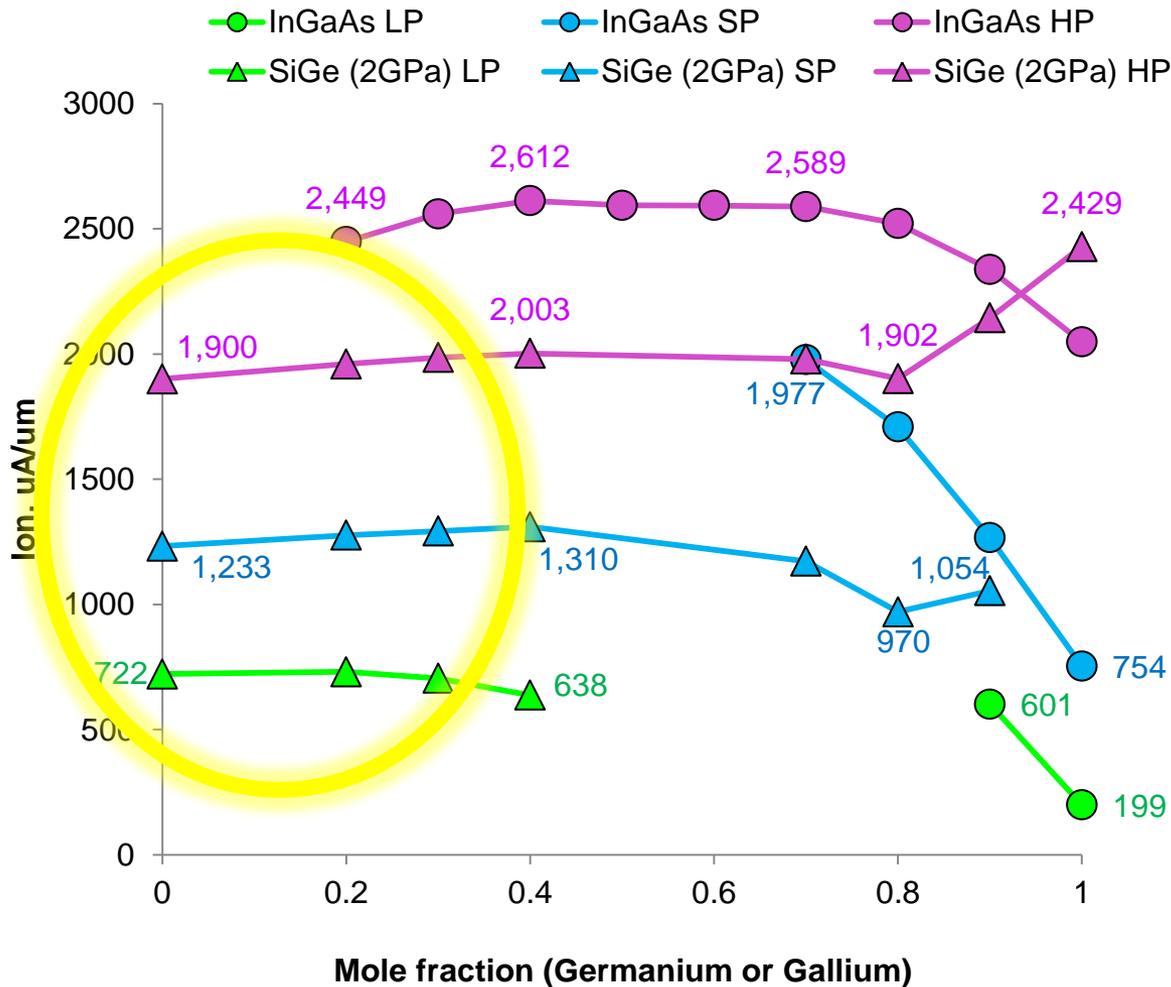


HP: Mid-range InGaAs

SP: 30% In InGaAs

LP: Si

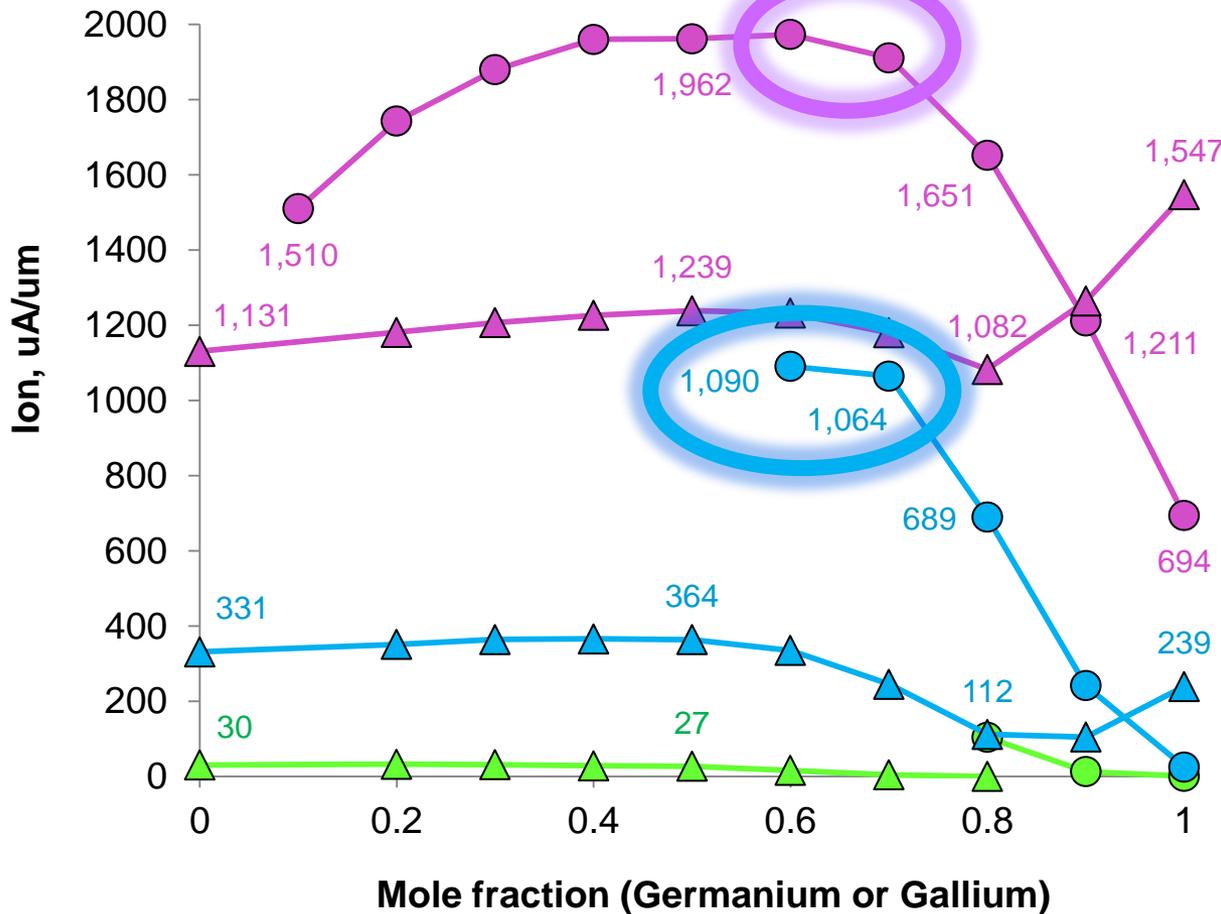
# Group IV vs III-V: Combination Champion



- Only Si, low Ge SiGe, and GaAs can match LP spec
- InGaAs with 10% In has competitive performance, but is too sensitive to In content
- This would bring severe variability
- So, silicon looks the best...
- SiGe with low Ge % can be used for stress engineering

# 0.5 V Vdd Instead of 0.7 V Vdd

● InGaAs LP      ● InGaAs SP      ● InGaAs HP  
▲ SiGe (2GPa) LP      ▲ SiGe (2GPa) SP      ▲ SiGe (2GPa) HP



- InGaAs with 30% In really shines at SP and HP specs
- Nobody can pull off LP at 0.5 V Vdd. Would you like your iPhone to be ~30x slower?
- To have 0.5 V Vdd, variability has to go down ~2x. That is a stretch.
- The best InGaAs composition has Si-like bandgap

# Summary



- It is a close race, no clear winner
- The best choice depends on particular chip spec